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TRANSMITTAL FORM <i>(to be used for all correspondence after initial filing)</i>	Application Number	10/699,079	
	Filing Date	October 31, 2003	
	First Named Inventor	Ziyun Wang	
	Group Art Unit	2826	
	Examiner Name	TBA	
Total Number of Pages in This Submission		Attorney Docket Number	ATMI-594-CIP

ENCLOSURES (check all that apply)		
<input type="checkbox"/> Fee Transmittal Form	<input type="checkbox"/> Assignment Papers (for an Application)	<input type="checkbox"/> After Allowance Communication to Group
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<input type="checkbox"/> Amendment / Reply	<input type="checkbox"/> Licensing-related Papers	<input type="checkbox"/> Appeal Communication to Group (Appeal Notice, Brief, Reply Brief)
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SIGNATURE OF APPLICANT, ATTORNEY, OR AGENT	
Firm or Individual name	William F. Ryann, Reg. No. 44,313
Signature	
Date	July 26, 2004

CERTIFICATE OF MAILING	
I hereby certify that this correspondence is being deposited pursuant to 37 C.F.R. 1.8 in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on this date: 7-26-04	
Type or printed name	Lee Ann DiLallo
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ATMI-594-CIP
Customer ID No. 25559

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Ziyun Wang, et al.

Group Art Unit: 2826

U.S. Application No.: 10/699,079

Examiner: TBA

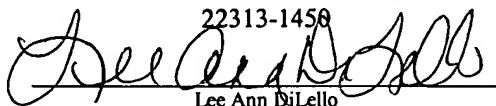
Filed: October 31, 2003

Title: COMPOSITION AND METHOD FOR LOW TEMPERATURE DEPOSITION OF
SILICON-CONTAINING FILMS

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Lee Ann DiLello

July 26, 2004
Date

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☐ 1. This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required in accordance with 37 CFR § 1.56 and § 1.97(b).

☒ 2. This Information Disclosure Statement is being filed more than three months after the U.S. filing date, but before the mailing date of the first Office Action on the merits.

☒ a. I hereby certify that each item of information contained in this Information Disclosure Statement was the first citation of such item by a foreign patent office in a counterpart foreign application, which occurred no more than three months prior to filing the Information Disclosure Statement. 37 C.F.R. §1.97(e)(1).

☐ b. I hereby certify that no item of information in this Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to my knowledge after making reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this Information Disclosure Statement. 37 C.F.R. §1.97(e)(2).

☐ c. Attached is our check no. ____ in the amount of \$180 in payment of the fee under 37 C.F.R. §1.17(p). Please credit or debit Deposit Account No. 50-0860 as needed to ensure consideration of the disclosed information. Two duplicate copies of this paper are attached.

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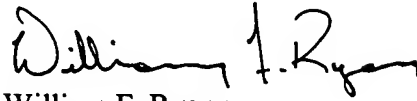
☐ a. I hereby certify that each item of information contained in this Information Disclosure Statement was the first citation of such item by a foreign patent office in a counterpart foreign application which occurred no more than three months prior to filing the Information Disclosure Statement. 37 C.F.R. §1.97(e)(1).

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☐ 4. (other):

Applicant does not believe that any additional fee is due in connection with the foregoing. However, any deficiencies may be charged to the deposit account 50-0860.

Respectfully submitted,

A handwritten signature in black ink, appearing to read "William F. Ryann". The signature is fluid and cursive, with the first name "William" and last name "Ryann" clearly distinguishable.

William F. Ryann
Registration No. 44,313
Attorney for Applicant

Date: July 26, 2004
Advanced Technology Materials, Inc.
7 Commerce Drive
Danbury, CT 06810
Agent Ref: ATMI-594-CIP



FORM PTO-144		US Department of Commerce Patent and Trademark Office		ATTORNEY DOCKET NO. ATMI-594-CIP		SERIAL NO. 10/699,079	
INFORMATION DISCLOSURE STATEMENT (use several sheets if necessary)				APPLICANT Ziyun Wang, et al,			
				FILING DATE October 31, 2003		GROUP 2826	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		PATENT NUMBER	ISSUE DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	PUBLICATION DATE	COUNTRY	CLASS	SUBCLAS S	TRANSLATION YES NO
							X (abstract only)
OTHER DOCUMENTS (Including Author, Title, Journal-Date, Page Number, Etc.)							
	AA	Schuh, et al. "Disilanyl-Amines-Compounds Comprising the Structural Unit Si-Si-N, as Single-Source Precursors for Plasma-Enhanced Chemical Vapour Deposition (PE-CVD) of Silicon Nitride, Z, anorg. Allg. Chem. 1993, Vol. 619, pages 1347-1352.					
Continue on Page							
EXAMINER					DATE CONSIDERED		
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.							